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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:	Leonel R. Arana et al.	§	Art Unit:	2813
Serial No.:	10/807,836	§	Examiner:	Heather Anne Doty
Filed:	March 24, 2004	§	Docket:	ITL.1133US P19113
For:	Microfabricated Hot Wire Vacuum Sensor	§	Assignee:	Intel Corporation

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 20051108

Sir:

In response to the office action mailed November 16, 2005, please amend the above-referenced patent application as follows:

Date of Deposit: January 12, 2006
I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.
Cynthia L. Hayden
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